**Introduction of** *µm***- and** *nm***-sized Semiconductor Raman scattering** 

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# Introduction Semiconductor Raman Scattering Example: Strain and Concentrations Raman Scattering of Nano-Sized Semiconductor (Dot, Wire and Layers) Summary



#### What is Raman?



Sir Chandrasekhara Venkata Raman
 1930 Nobel Price Winner





Mie Scattering: Particles, Rayleigh Scattering: Particles  $(10^{-2} \sim 10^{-3})I_i$ Brillouin Scattering: Acoustic Phonon  $(10^{-6} \sim 10^{-9})I_i$ Raman Scattering: Optical Phonon  $(10^{-6} \sim 10^{-9})I_i$ 







#### **Raman Lineshapes:**

Gaussian
Lorentzian
Fano
Asymmetry
???

# Raman Shift Linewidth



#### **SiGe Alloy Dot on Si(001)**



#### **Strain in Embeded Layer**



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#### **MBE Grown Relaxed SiGe alloy**



LT-Si 500 °C (#323)



LT-Si 550 °C (#320)



LT-Si 600 °C(#319)



LT-Si 400 °C (#321)





Physics of NTNU



LT-Si 450 °C (#322)



L-W Lei et.al. ICPS 2002





#### Strain & Ge Content of Alloy

#### Raman Shift of $Si_{1-x}Ge_x$ Alloy for x < 0.4:

$$\omega_{siSi} = 520.5 - 62x - 815\varepsilon$$
$$\omega_{siGe} = 400.5 + 14.2x - 575\varepsilon$$
$$\omega_{GeGe} = 282.5 + 16x - 385\varepsilon$$

$$\varepsilon = \delta l/l$$

J. Groenen, et.al. Appl. Phys. Lett. (1997)



	457nm		488nm		514nm	
sample	x	(%)	x	(%)	x	(%)
# 319	0. 3	-2.1	0. 3	-1.9	0.3	-0.04
(LT600°c)	±0.03	±0.06	±0.03	±0.06	±0.02	±0.003
# 320	<mark>0.3</mark>	-2.3	0. 3	-2.1	0.3	-0.7
(LT550°c)	±0.03	±0.06	±0.02	±0.03	±0.02	±0.003
# 323	0. 3	-1.6	0.3	-1.4	0. 3	-1.6
(LT500°c)	±0.03	±0.06	±0.02	±0.03	±0.02	±0.003
# 322	0. 3	-0.7	0. 3	-1.4	0. 3	-3.1
(LT450°c)	±0.03	±0.06	±0.03	±0.06	±0.03	±0.006
# 321	0. 3	-2.3	0. 3	-1.6	0. 3	-2.1
(LT400°c)	±0.03	±0.06	±0.03	±0.06	±0.02	±0.003
# 332	0.3	-1.6	0.3	-1.4	0. 3	-2.6
(LT350°c)	±0.03	±0.06	±0.03	±0.06	±0.03	±0.006

Results:  $x = 0.30, \Sigma = -0.16\%$ 



#### Spectra excited by various Energies



**1**0

#### **Absorption Coefficient**



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#### **GeSi/Si Micro-Horns**

Si cap	2nm				
Ge0.1 Si 0.9	25nm				
Ge0.4 Si0.6	20nm				
Si buffer	100nm				
Si substrate					

Fig.1 sample before etching





#### **Micro-Horn Images**



Sample 725



Sample 725





#### Raman Spectra:



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#### Strain & 1/D



$$\omega_{Si-Si} = 520.5 - 62x - 815\varepsilon - C \cdot \frac{1}{D}$$





#### **Spherical Si Quantum Dots**



(a)

(b)



Y-C Liao, *et.al.*, Appl. Phys. Lett. 77, 4328 (2000). C-W Lin, *et.al.*, J. of Appl. Phys. 91, 1525 (2002).





#### **Raman Study of Si Dots' Size**

Thermal Evaporation Growth Si Dots



D.-Y. Chien, et.al., ICORS 2002



Size of Dots:

$$I(\omega) = \int_{0}^{1} \frac{d^{3}q |C(0,\bar{q})|^{2}}{[\omega - \omega(q)]^{2} + (\Gamma_{0}/2)^{2}}$$

 $\omega(q) = \left[A + B\cos(\pi q/2)\right]^{1/2}$ 

$$|C(0, \vec{q})|^2 \cong e^{-q^2 L^2 / 4}$$





#### **Raman Spectra of GaN Wire**



H-L Liu, et.al., Chem. Phys. Lett. 345, 245-251 (2001)



#### **LO-Phonon and Plasma Coupling**



#### **CDF and IIF Mechanism**

$$I(\omega) = \int_{0}^{q_{\max}} dq F(q) \cdot q^{2} S(\omega, q) \operatorname{Im}\left(\frac{-1}{\varepsilon(\omega, q)}\right)$$
$$S_{CDF}(q, \omega) \propto (1 - e^{-\hbar\omega/k_{B}T})^{-1} \cdot \left(\frac{(\omega_{LO}^{2} - \omega^{2})}{(\omega_{TO}^{2} - \omega^{2})}\right)^{2}$$

$$S_{IIF}(q,\omega) \propto (1-e^{-\hbar\omega/k_BT})^{-1}$$

$$F(q) = \left(\frac{4\pi}{q^2 + q_{FT}^2}\right)^2$$



#### **Coupled Dilectric Constant:**

$$\mathcal{E}(q,\omega) = \mathcal{E}_{\infty} + \chi_{Phonon} + \chi_{Linhard}(q,\omega)$$

$$\chi_{Phonon} = \varepsilon_{\infty} \frac{\omega_{LO}^2 - \omega_{TO}^2}{\omega_{TO}^2 - \omega^2 - i\omega\gamma}$$

#### Lattice-Vibration Contributions

$$\chi_{Linhard}(q,\omega) = \frac{(1-i\Gamma/\omega)[\chi^{0}(q,\omega+i\Gamma)]}{1+(i\Gamma/\omega)[\chi^{0}(q,\omega+i\Gamma)/\chi^{0}(q,0)]}$$

**Plasma-Oscillation Contributions** 



## **Fitting Results**



Heavy damping  $\Gamma$ =200 cm<sup>-1</sup> Impurity Desinty: ~2X10<sup>19</sup> cm<sup>-3</sup>





#### **Ge/Si MBE-Grown Superlattice**





#### **Folded LA Phonon**







## Thickness of Ge and Si laryer Rytov theory



$$\omega = V_{SL} \left( \frac{2\pi m}{d} \pm q \right)$$



C.-H. Lin, C.-T. Chia and H. H. Cheng, ICOR2002

#### Folded LA Intensity:



 $\eta = \frac{\omega_m(n_m+1)}{\omega_0(n_0+1)}$ 

s1n<sup>-</sup>(*mπ* 

 $\pi^2 m^2$ 

 $(P_b^1)$ 

## Layer Thickness

樣品21	Si厚度 (nm)	Ge厚度 (nm)	厚度比d <sub>1</sub> /d	超晶格週期 <i>d</i> (nm)
TEM圖	15±2	3±2	0.83	18±4
光譜擬合	17.5±0.6	2.40±0.08	0.88	<b>19.9±0.7</b>
樣品22				
TEM圖	17±2	2±2	0.90	19±4
光譜擬合	15.8±0.5	2.30±0.08	0.90	<b>18.1±0.6</b>
樣品23				
TEM圖	20±2	2±2	0.91	22±4
光譜擬合	<b>19.6±0.7</b>	2.50±0.09	0.89	<b>22.1±0.8</b>



#### **Continuous Emission:**

#### Sample 22 300K 532nm Laser



#### Theory of Continuous Emission:

$$I_{(\omega)} \cong \sum_{q_Z} \frac{q_z^2}{q_z} \frac{\sin^2 \frac{aq_Z}{2}}{\left(\frac{aq_Z}{2}\right)^2} \times \left(n_q + 1\right) \left(\begin{array}{cc} l - s - q \end{array}\right)$$

$$\times \left| \sum_{N} \left( \Omega_N + i \frac{\gamma_e + \gamma_h}{2} \right)^{-1} \left( \Omega_N - \iota + \iota_s + i \frac{\gamma_e + \gamma_h}{2} \right)^{-1} \times \frac{4N^2}{4N^2 - \left( \frac{aq_Z}{2} \right)^2} \right|$$



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#### **Continuous Emission Fitting**



Resonant Energy : 2.34 eV



#### **Room Temperature Luminescence**

Sample23 300K







#### **Visible Lasers + Raman Spectrometers**

Can completely resolve the Physics properties of semiconductor from Raman-Phonon Lineshapes.

Right energy laser Good-resolution spectrometer





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# 目前有合作關係的伙伴

#### 師大:鄭秀鳳、陸健榮、劉祥麟教授 清華:林諭男教授 台大:李嗣岑、鄭鴻祥、張玉明教授 新竹師院:林志明教授



# 即將會有合作關係的伙伴



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